

Application No. 10/005,188

AMENDMENTS TO THE SPECIFICATIONIn the Specification

Please substitute the following amended paragraph(s) and/or section(s) (deleted matter is shown by strikethrough or double brackets and added matter is shown by underlining):

Paragraph bridging pages 1 and 2:

The semiconductor processing industry is moving toward utilization of larger and heavier wafers, specifically ~~[[30]]~~ 300 mm wafers. Transport modules for such modules, utilize a front opening door for insertion and removal of the wafers as opposed to a bottom door that drops downwardly from the module. The door would not support the load of the wafers, rather a container portion which would include a clear plastic (such as polycarbonate) shell and other members for supporting the wafers molded from a low particle generating plastic (such as ~~polyetheretherketone~~ polyetheretherketone) would carry the load of the wafers. Such container portions necessarily are made from multiple components assembled together.

First paragraph on page 5:

~~Such machine interfaces~~ FIG. 1 illustrates a prior art wafer container 30. Such a carrier includes a container portion 32, a door 34, ~~[[and]]~~ a robotic flange 36, and manual handles 44. Such wafer carriers have a plurality of horizontal wafer slots formed by plurality of pairs of wafer shelves positioned in the container portions. FIG. 2 shows another style of wafer

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container, similarly having the container portion 32, handles 44, and also illustrating a machine interface 48 configured in a first configuration as a kinematic coupling. The kinematic coupling has three grooves 49 such as are illustrated in U.S. Patent Nos. 5,755,332; 5,944,194; 6,010,008; and 6,010,009. These patents are all incorporated herein by reference. Kinematic couplings have proven to be an effective machine interface and are the industry standard for 300 mm wafer carriers. The kinematic coupling machine interfaces have cooperating portions, one portion has three projections, such as partial spheres, positioned at the three points of an equilateral triangle, and the other portion has three grooves that receive the partial spheres to repeatably and accurately seat the two portions together. Such a kinematic coupling portion may be separately formed, such as by injection molding, and suitably attached to the bottom of a container portion. Such a portion is illustrated in U.S. Patent No. 6,216,874, commonly owned with the instant application. Said patent is hereby incorporated by reference. Alternatively, the machine interface may be an integral part of the container portion or may be part of the structural framework as disclosed in U.S. Patent No. 6,010,008. A stacking adaptor 50 is illustrated in position to engage with the kinematic coupling in FIG. 2.

Paragraph bridging pages 5 and 6:

FIGS. 3, 4, and 5 ~~illustrates~~ illustrate a preferred embodiment of a stacking adaptor. The plate has a body portion 54 with a top side 55 having kinematic coupling portion 56, and a bottom side 58 having an attachment portion 59. The kinematic coupling portion comprises at least three rounded projections 60, and as illustrated, has an addition set of three supplemental

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projections 62. Three legs 63 extend horizontally and each leg has at least one of the at least three projections. The projections may be separately formed and attached with suitable fasteners 68, or may be integrally molded with the body portion. The bottom side 58 includes three wafer carrier contact portions 66 that are placed proximate to the kinematic coupling projections on the top side. Additionally, a contact portion 70 is configured to correspond with the base of a robotic flange to cooperatively engage with the top of a wafer carrier in place of the robotic flange. The adaptor also has a hook shaped member 71 that functions as a detent.

First full paragraph on page 6:

FIG. 6 illustrates the receptacle portion 73 of a container portion 32 that receives accessories such as the robotic lifting flange or the stacking adaptor plate. The receptacle portion may have a pair of sliding guide members 72, 74 that have [[an]] undercut portions 75, 76 that define slots 78, 79. The undercut may be at an angle to the horizontal to allow the accessory to wedge into position providing further securement of same on the container portion. Also a latching portion 80 may receive a detent on the accessories to releaseably secure the accessory at the receptacle portion. FIG. 6 also illustrates a pair of wafer carriers in the process of being stacked on top of one another utilizing a stacking adaptor in accordance with the invention.